

Abstract

Several yield issues have been caused by wafer cassettes which were in poor condition. During fabrication, wafers spend well over half of their lives in cassettes, so there is a large potential for such yield issues. Advanced techniques have enabled better (and automatic) tracking of cassette related history. DMOS-5 has taken advantage of this to set up a flexible system to allow the engineer to include details about the wafer cassette in any yield study in the CMP area. This system is capable of expansion. In this paper we will present the attributes and features of our tracking system.

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